



3723
PATENT
2185-0599P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Masayuki TAKASHIMA et al. Conf.: 5671
Appl. No.: 10/024,307 Group: 3723
Filed: December 21, 2001 Examiner: E. MORGAN
For: POLISHING PAD, POLISHING APPARATUS AND
POLISHING METHOD USING THE SAME

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APR 12 2004

REPLY UNDER 37 C.F.R. 1.111

TECHNOLOGY CENTER #0700

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

April 5, 2004

Sir:

In response to the Office Action dated October 6, 2003, the period for responding having been extended three (3) months until April 6, 2004, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

This amendment includes:

Amendments to the Specification;

Amendments to the Claims; and

Remarks.

04/06/2004 NROCHA1 00000032 10024307

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